MScs

- **George Kokkoris**
  Simulation of SiO_2 and Si features in fluorocarbon plasmas (1999)

- **George Kordogiannis**
  Dry etching of polymeric materials using lithography in high density inductively coupled plasma reactor (2000)

- **Alexandros Koulides**
  Computational methods for plasma etching of contact holes of integrated circuits (2001)

- **Konstantinos Boukouras**
  Etching of silicon surfaces in high density plasma reactor and study of surface and line edge roughness (2003)

- **Olga Brani**
  Study of silicon and silicon containing polymer surfaces after plasma treatment (2004)

- **Evrymahos Matrozos**
  Selective deposition of fluorocarbon films and application in protein arrays (2005)

- **Panagiotis Papassimakis**
  Fabrication and simulation of microstructures by plasma processing (2005)

- **Katerina Tsougeni**
  Modification of PDMS surfaces in O2-based plasmas (2005)

- **Paraskevi Geka**
  Modeling of the gas phase of oxygen plasma discharges with global zero dimensional models (2006)

- **Eleni Zakka**
  Plasma etching of composite materials: Stochastic simulation of roughness formation (2006)

- **Paraskevi Xydi**
  Simulation of etching using the narrow band level set method (2006)

- **Panagiotis Angelikopoulos**
  Monte-Carlo roughening during thin film plasma etching (2006)